





Precursors

PRECURSOR

Si PRECURSOR
 HCDS : Hexachlorodisilane
 OCTS : Octachlorotrisilane
 3DMAS : Tris(dimethylamino)silane
 BDEAS : Bis(diethylamino)silane

III-V PRECURSOR
 TBAs : Tertiarybutylarsine
 TMA : Trimethylaluminum
 TMI : Trimethylindium
 TMG : Trimethylgallium

METAL PRECURSOR
 TEMAZ : Tetrakis(ethylmethylamino)zirconium
 TDMAZ : Tetrakis(dimethylamino)zirconium
 Cp-Zr : Tris(dimethylamino)cyclopentadienyl Zirconium
 Adv. Zr : Advanced zirconium precursor
 TDMAH : Tetrakis(dimethylamino)hafnium
 TDMAT : Tetrakis(dimethylamino)titanium
 PDMAT : Pentakis(dimethylamino)tantalum
 Ru(EtCp)₂ : Bis(ethylcyclopentadienyl)ruthenium(II)
 TiCl₄ : Titaniumtetrachloride

R&D CENTER

Gas & Precursor Development
 (New applications/ Materials)
 Customized purification Lab.
 (UHP Grade, Mixed materials)
 Deposition R&D Lab.
 Surface Analysis Lab.
 Pilot Plant



Yangcheong Plant

PRECURSOR PLANT

Explosion-proof structure
 Synthesis & UHP Purification
 Auto canister handling system
 Materials Analysis Lab.

“

Precursor is one of our new business portfolio. Currently completed Precursor plant and R&D Center set up in Yangcheong. These new high-tech facilities can strengthen our safety level and meet customers' needs on new materials.

”

PRODUCT LINE UP

Stock Sales	Product	Purity	Package		Manufacture type	Key para. (Impurity)
			Cylinder (L)	Valve type		
	Si2H6	4N8	49	DISS 632	Stock	SiH4, N2, H2O
	GeH4 Mix (10%)	4N8	47	DISS 632	Stock	Concentration
	C2H4	5N	47	DISS 724	Stock	H2O, N2, OHC
	CF4	5N	47, 440	JIS 22R, DISS 716	Stock	H2O, N2, OFC
	CH2F2	4N	47	JIS 22L	Stock	H2O, N2, OFC

Precursors	Product	Purity	Package		Manufacture type	Key para. (Impurity)
			Cylinder (L)	Valve type		
	HCDS	6N	19L, 38L	Customized	Synthesis, Distillation	Assay, Metal
	BDEAS	6N	19L	Customized	Distillation	Assay, Metal, Cl-
	TiCl4	7N	19L	Customized	Distillation	Assay, Metal, Moisture



THANK YOU